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Li Yang
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Introduction

The 6th International Symposium on Advanced Optical Manufacturing and Testing Technology (AOMATT) was held 26–29 April 2012 at the Xiamen International Conference Center, Xiamen, China.

AOMATT 2012 was kicked off on April 26 with a formal opening ceremony. The ceremony started with the introduction of VIP guests, symposium chairs, and conference chairs, followed by opening speeches by Prof. Liwei Zhou, AOMATT 2012 Symposium Chairman, Prof. Bin Xu, Vice President of IOE, sponsor of AOMATT2012, and Dr. H. Philip Stahl, Vice President of SPIE, technical cosponsor of AOMATT2012. Plenary sessions started immediately after the conclusion of the opening ceremony. There were a total of 10 plenary presentations: Dr. H. Philip Stahl, 2012 SPIE Vice President and NASA Marshall Space Flight Center (USA); Prof. Hiroki Kuwano, 2012 President of Japanese Mechanics Society and Director of Micro/Nano Center, Tohoku University (Japan); Dr. Fritz Klocke, President of Fraunhofer Institute for Production Technology IPT (Germany); Dr. James Burge, Professor of Optical Sciences and Astronomy at the University of Arizona (USA); Dr. Eric Ruch , SAGEM (France); Dr. Tilmann Heil, Director of System Engineering, Carl Zeiss SMT GmbH (Germany); Prof. W. B. Lee, Professor of Manufacturing Engineering and Director of Advanced Technology Manufacturing Research Centre, Hong Kong Polytechnic University; Dr Fengzhou Fang, Professor of Precision Measurement Technology and Instruments at Tianjin University (China); Prof. Shengyi Li, Professor of Mechatronics and Automation at the National University of Defense Technology (China). More than 1,000 people attended the opening ceremony and full-day plenary sessions.

More than 1,000 abstracts were submitted to AOMATT2012, and from these about 500 oral and poster papers were selected. Oral papers were presented in 8 parallel conferences on April 27 and 28. An all-symposium poster session was held in the afternoon of April 28. All of the parallel conference sessions and the poster session were well attended. Authors and attendees had active discussions and exchange of ideas throughout the symposium. Many papers presented cutting-edge research and development work in optical design, manufacturing, and testing. The success of AOMATT2012 continued the tradition of focus and excellence of this biannual international topical symposium in China.

We would like to express our sincere appreciation to COS - The Chinese Optical Society, IOE - Institute of Optics and Electronics, Chinese Academy of Sciences, and SPIE for sponsoring and supporting AOMATT2012. We want to thank all authors and participants for their contributions to the symposium and sharing their research with colleagues around the world. The 7th AOMATT is planned for 2014.

We look forward to seeing everyone at AOMATT2014. Please watch for the Call for Papers and symposium announcements on SPIE and IOE web sites.

Li Yang
Jinxue Wang
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